## **Amendments to the Claims:**

The following listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (Currently Amended) A sol having a pH of 1 to 6 or 8 to 13 pH of 3 to 6 or 8 to 10 in which particles are dispersed in a medium, wherein the particles have a particle size of 50 to 150 nm, have a specific surface area of 2 to 200 m<sup>2</sup>/g, and comprise as a main component crystalline cerium oxide of the cubic system and as an additional component a lanthanum compound, neodymium compound or a combination thereof, wherein the additional component is contained in X/(Ce + X) molar ratio of 0.005 to 0.15 in which X is lanthanum atoms, neodymium atoms or a combination thereof.
- 2. (Original) A sol according to claim 1, wherein the additional component is a lanthanum compound.
- 3. (Original) A sol according to claim 1, wherein the additional component is a neodymium compound.
  - 4-9. (Canceled)
- 10. (Currently Amended) An abrasive containing a sol having a pH of 1 to 6 or 8 to 13pH of 3 to 6 or 8 to 10 in which particles are dispersed in an aqueous medium in a range of 0.1 to 50 wt%, wherein the particles have a particle size of 50 to 150 nm, have a specific surface area of 2 to 200 m²/g, and comprise as a main component crystalline cerium oxide of the cubic system and as an additional component a lanthanum compound, neodymium compound or a combination thereof, wherein the additional component is contained in X/(Ce + X) molar ratio of 0.005 to 0.15 in which X is lanthanum atoms, neodymium atoms or a combination thereof.
  - 11. (Canceled)

- 12. (Previously Presented) An abrasive according to claim 10, wherein the additional component is a lanthanum compound.
- 13. (Previously Presented) An abrasive according to claim 10, wherein the additional component is a neodymium compound.
  - 14. (Canceled)
  - 15. (Canceled)
- 16. (Previously Presented) An abrasive according to claim 10, which is used for polishing a substrate which comprises silica as a main component.
- 17. (Previously Presented) An abrasive according to claim 10, which is used for polishing a rock crystal, a quartz glass for photomask, a semiconductor device or a hard disk made of glass.
- 18. (Previously Presented) An abrasive according to claim 10, which is used in a step of polishing an organic film, a step of polishing Inter Layer Dielectric (ILD) or a step of shallow trench isolation, for polishing a semiconductor device.